

Crystal Growth by Floating Zone Technique

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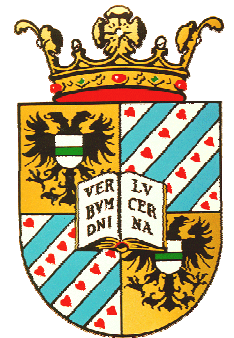
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Outline

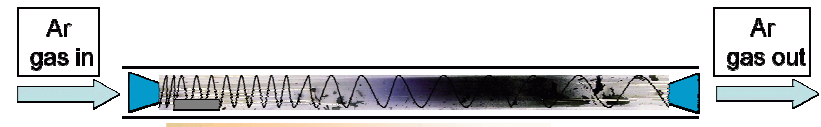
- Introduction to Crystal Growth Techniques
 - Polycomponents
 - Monocomponent
- Liquid-Solid Monocomponent Growth Techniques
- Floating-Zone Technique
 - Description of the Equipment
 - Sample Preparation
 - Growth Preparation
 - Sample Growth
- Characterization
 - Crystallinity
 - Determination of composition
- Bibliography
- Conclusions

Crystal Growth Techniques (1)

- Polycomponents
 - Solid-Solid
 - Precipitation from solid solution
 - Liquid-Solid
 - Growth from solution (evaporation, slow cooling, temperature differential)
 - Growth by reaction (same media, temperature change, concentration change)
 - Gas-Solid
 - Growth by reversible reaction (temperature change, concentration change)
 - Growth by irreversible process (epitaxial process)

Crystal Growth Techniques (2)

- Monocomponent
 - Solid-Solid
 - Strain annealing
 - Devitrification
 - Polymorphic-phase change
 - Gas-Solid
 - Sublimation / Condensation
 - Sputtering
 - Liquid-Solid (melt)
 - Directional solidification
 - Cooled seed
 - Pulling
 - Zoning
 - Verneuil

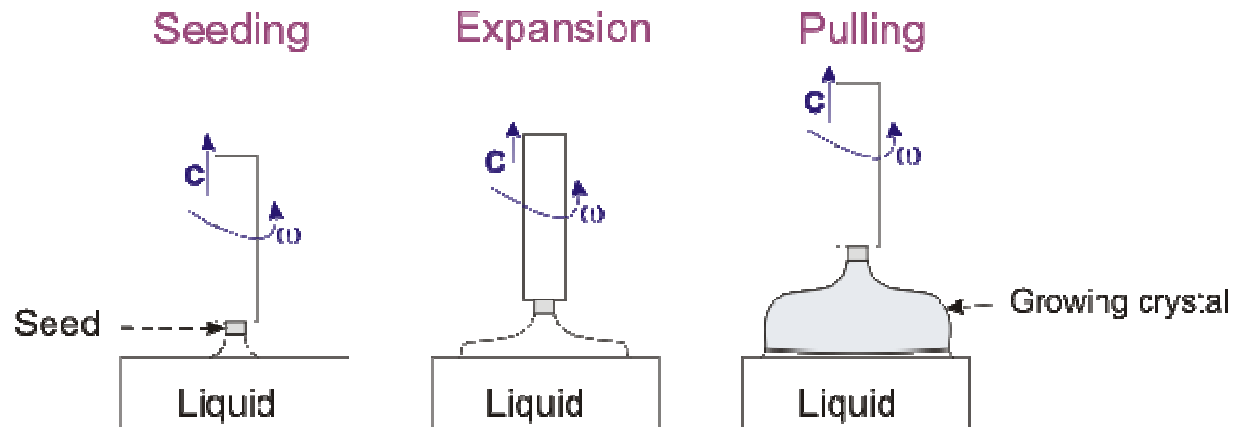


Conservative

Non-conservative

Melt Growth (1)

Czochralski



Advantages

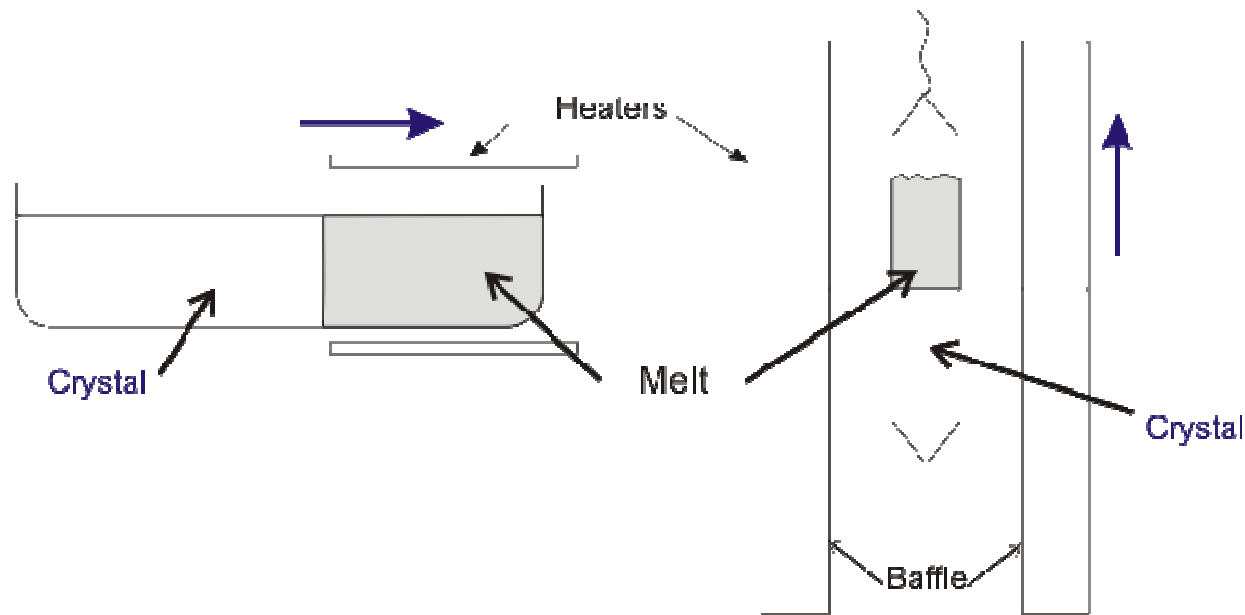
- Growth from free surface
- Growth of large *oriented* single crystals
- Convenient chemical composition
- Control of atmosphere

Limitations

- High vapor pressure materials
- Liquid phase encapsulation
- Possible contamination of the melt by the crucible
- No reproducibility of the crystal shape

Melt Growth (2)

Bridgman



Advantages

- Simple technique
- Control of vapor pressure
- Containers can be evacuated and sealed
- Control of shape and size of crystals
- Stabilization of thermal gradients

Limitations

- Confinement
- Thermal expansion container vs crystal
- Crystal perfection is not better than the one of the seed
- No visibility

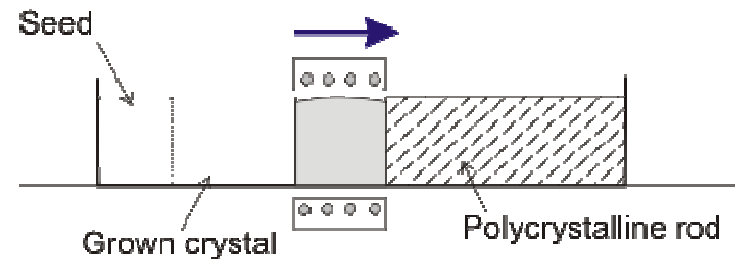
Melt Growth (3)

- Traveling Zone
- T Gradient close to the growth interface
- Pfann (1952), purification technique

Advantages

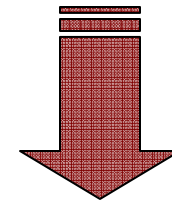
- Control of impurities while growth
- Reduce contamination of the melt by the crucible
- Less heater power
- Uniform doping obtained by zone-refining
- Increase of grain size by zone refining

Zone-melting



Limitations

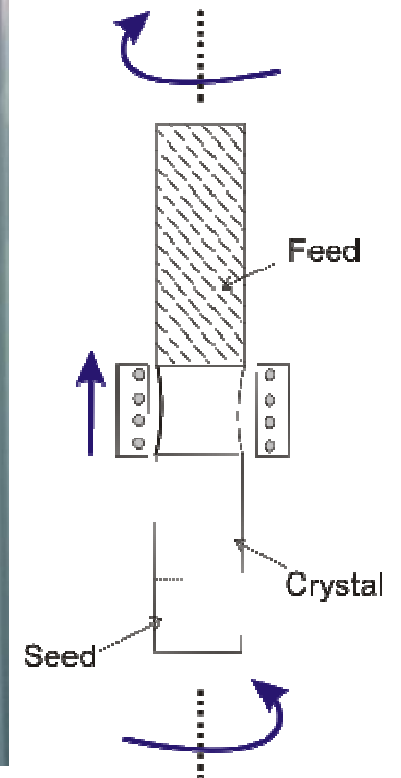
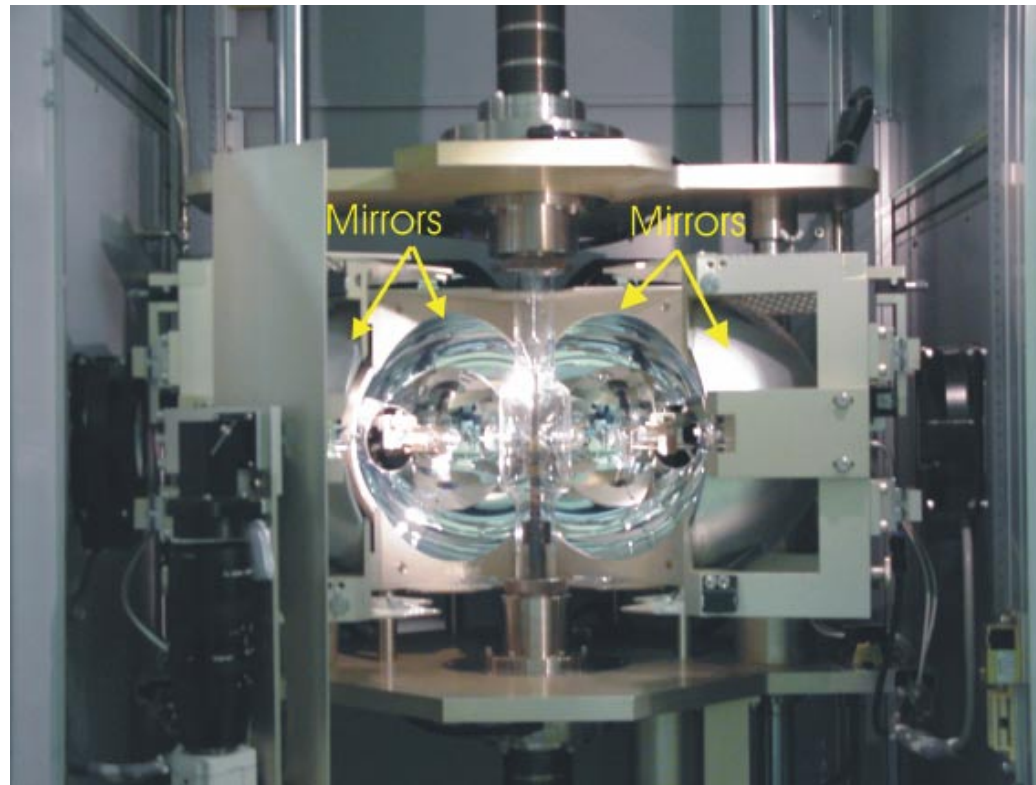
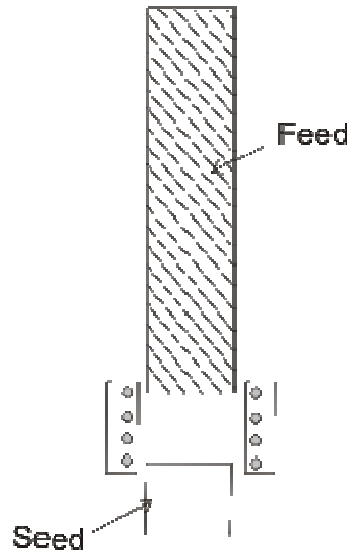
- Contamination from crucible
- Thermal and Volume expansion



Float Zone Technique (FZT)

FZT (1)

Setup



FZT (2)

Setup

2-mirror Halogen lamps
furnace

Max. Pressure = 3 atm

Max grown size: 80 mm
length, 8 mm diameter

Growth rates: 0.25 - 10
mm/hr

Power: 400 W - 3500 W
(2150°C)

4-mirror furnace

Halogen lamps (Uniform
heating, better spatial definition of
the hot zone)

Xenon HP lamp (Uniform
radial illumination; very well
defined vertical power profile)

Power: 800 – 6000 W
(2200°C)

Power: 5.4 kW
(2800°C)

Max. Pressure = 10 atm → Growth of
materials with higher vapor pressures.

Max grown size: 150 mm length, 10 mm
diameter (more for Xe-lamp)

Growth rates: From 0.1 to 20 mm/hr

Turbo pump → Vacuum down to 10^{-6} mbar

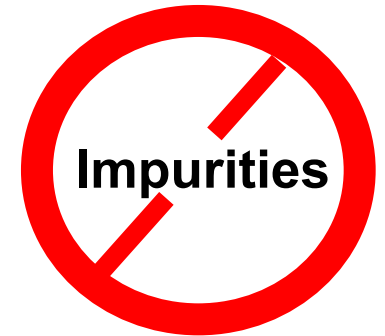
Sample chamber can be filled with inert, reductive, oxidizing atmospheres

FZT (3)

Sample Preparation

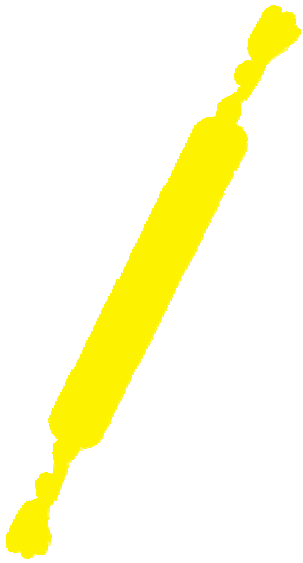
- Starting material:

- $\approx 20\text{g}$ of thoroughly ground powder
- Raw compound (RTiO_3)
- Annealed material (RMnO_3)
- Partially annealed material (RVO_3)



- Feed rod preparation:

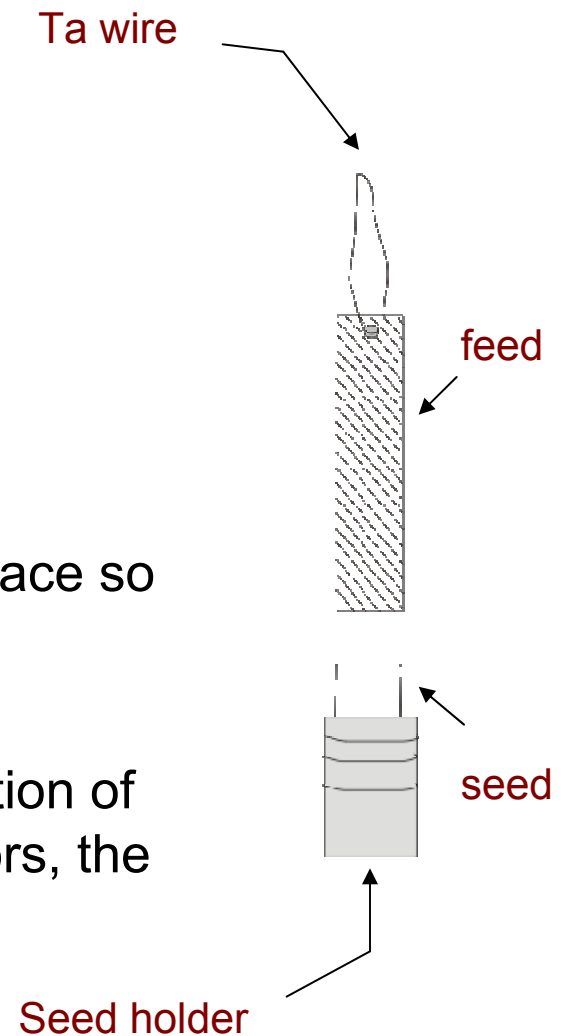
- Fill a rubber tube of desired diameter with the powder
- Slightly tight the end of the tube, make sure the diameter of the rod is constant
- Pump (progressively) the air remaining in the tube
- Seal the rubber tube
- Press the rod with an isostatic press (500 ~ 600 bar)
- Remove the rubber band



FZT (4)

Sample Preparation

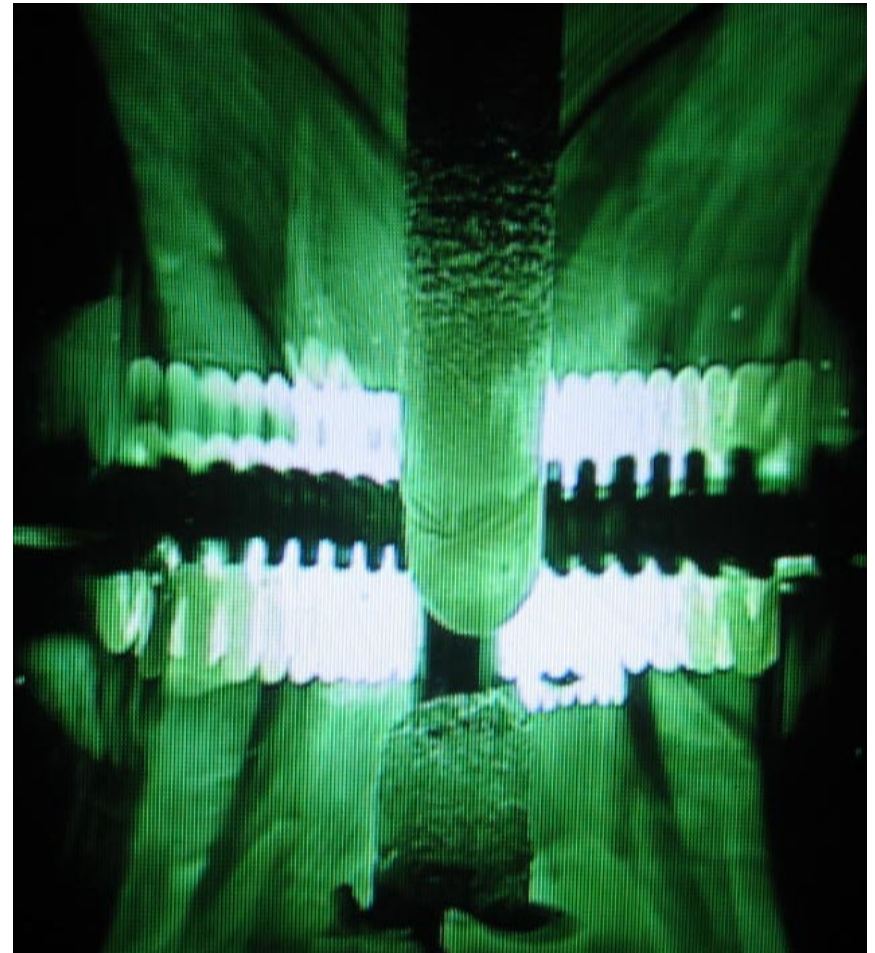
- Seed preparation:
 - Single crystal from a previous growth
 - Polycrystal from a previous growth
 - Part of the feed
 - Single crystal from a similar compound
 - Necking
- Rods of seed and feed are mounted in the furnace so as to be perfectly aligned.
- A very clean work environment for the preparation of the rods, the mounting in the furnace, the mirrors, the lamps, the quartz tube is extremely important



FZT (5)

Growth Preparation

- Evacuation of the sample chamber (10^{-6} mbar)
- Choice of atmosphere and pressure
 - RTiO_3 : 2 atm 95% Ar, 5% H_2
 - $\text{RMnO}_3_{\text{hex.}}$: 1 atm air + 0.5 atm O_2
 - $\text{RMnO}_3_{\text{orth.}}$: no evacuation, no flushing
 - RVO_3 : 1.5 atm Ar
 - TbMn_2O_5 : 6 atm O_2 .
- Sintering
 - RTiO_3 : 80% of growth power
 - $\text{RMnO}_3_{\text{hex.}}$: 80% of growth power
 - $\text{RMnO}_3_{\text{orth.}}$: 60-75% of growth power
 - RVO_3 : 60% Power
 - TbMn_2O_5 : 60% of growth power



FZT (6)

Growth Preparation

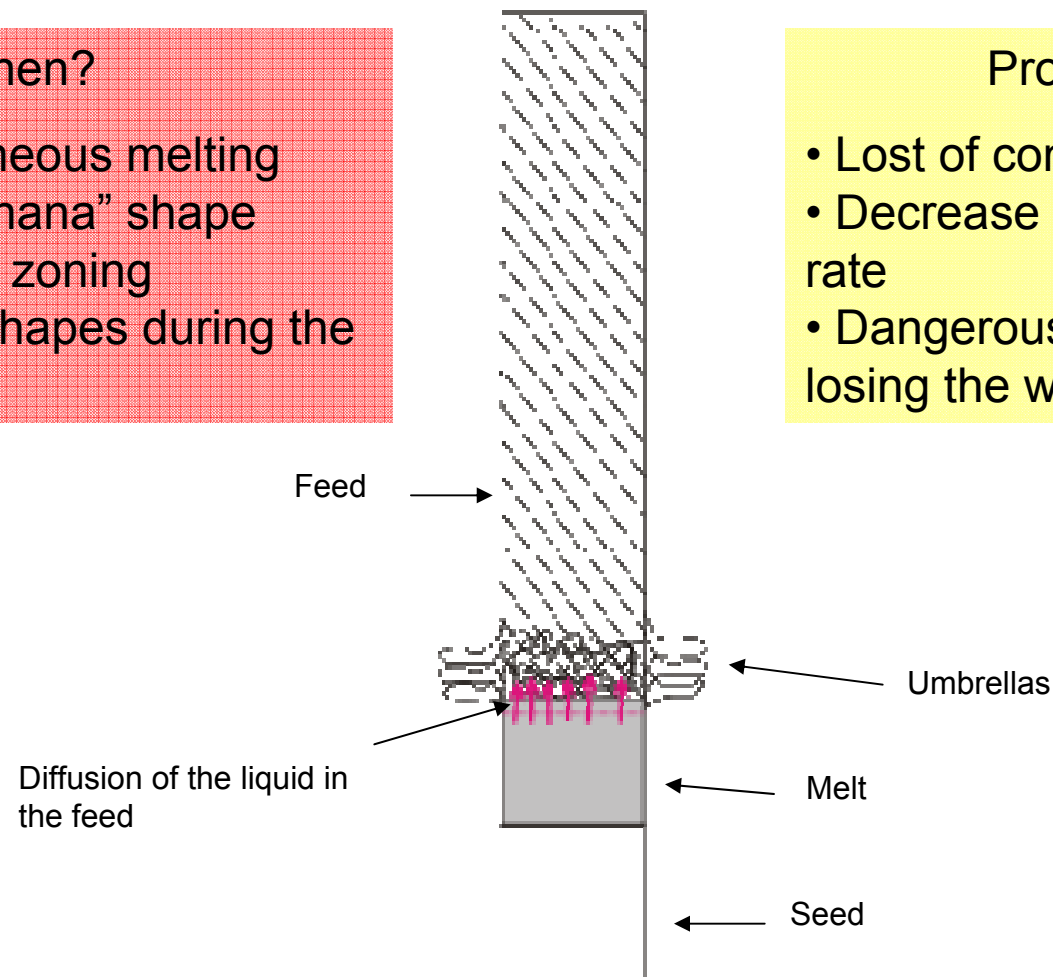
- Fast scanning (~ 30 mm/hr):

When?

- Inhomogeneous melting
- Rod in “banana” shape
- Insufficient zoning
- Umbrella shapes during the growth

Problem....

- Lost of composition
- Decrease of actual growth rate
- Dangerous, possibility of losing the whole rod



FZT (7)

Crystal Growth

- Equilibrium in crystal growth

- The crystal grown must be thermodynamically stable at T and P of crystallization.
- Dependence of the melting point on pressure:

$$\frac{dP}{dT} > 0 \quad \text{if } \Delta V > 0 \quad \text{and } \Delta S > 0 \quad \text{for a melting process}$$

From $\Delta H = T\Delta S$, $\Delta H > 0 \Rightarrow$ Melting is endothermic

$$\text{At equilibrium, } \Delta G = 0 \Rightarrow T_{eq} = \frac{\Delta H}{\Delta S}$$

Melting point unique for any given pressure

- Superheating is not possible
- Very slight supercooling required for growth

FZT (8)

Crystal Growth

- Distribution coefficient

$$k_0 \equiv \frac{a_{s(eq)}}{a_{l(eq)}} \equiv \frac{C_{s(eq)}}{C_{l(eq)}}$$

- k_0 ~ equilibrium constant if the crystal is neither growing nor dissolving
- $a_{s(eq)}$: Equilibrium activity in the solid
- $a_{l(eq)}$: Equilibrium activity in the liquid

During growth, k_{eff} = effective distribution coefficient

Try to reach $k_{eff} = 1!!!$

$$k_{eff} = \frac{C_{s(act)}}{C_{l(act)}}$$

Dependency

- growth rate
- diffusion constant of the material in the melt,
- width of the diffusion layer

FZT (9)

Crystal Growth

Control of the solvent in Traveling Solvent Float Zone technique:

Solvent used for lowering the melting point, or reduce incongruent melting....

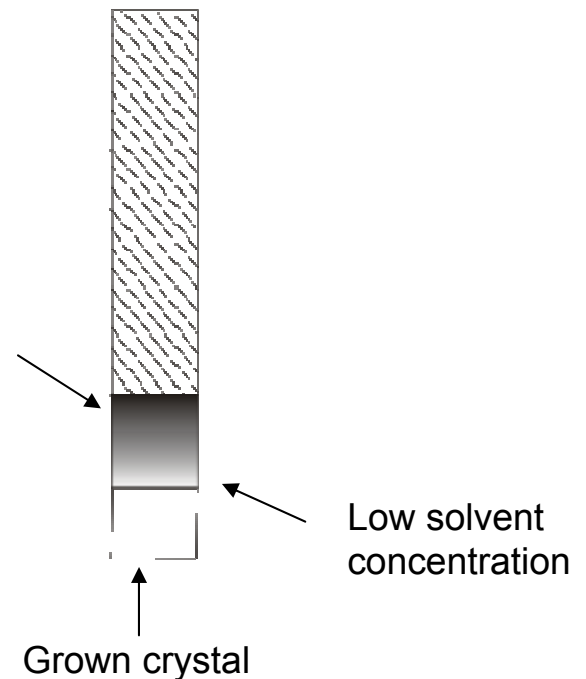


Goal: keep the solvent all along the growth

If $k_{\text{eff}} > 1$

- Depletion of the solvent concentration close to the growing crystal
- Bulk of melt richer in solvent than growth region

High solvent concentration



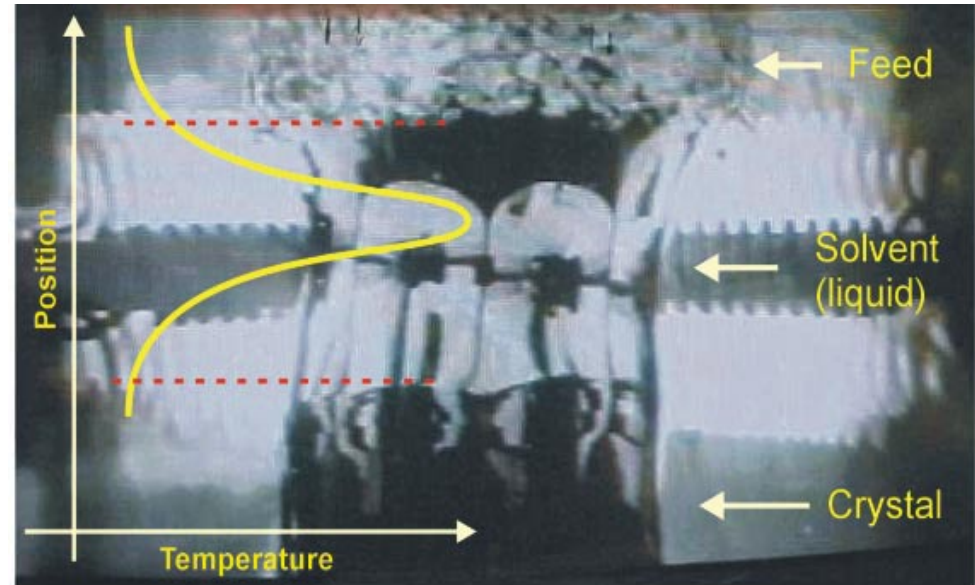
FZT (10)

Crystal Growth

- Stability conditions (Heywang-1956).

Include:

- ✓ surface tension,
- ✓ gravitational field,
- ✓ melt wetting the solid completely,
- ✓ negligible volume change



$$\lambda = l \sqrt{\frac{dg}{\sigma}} \quad \text{and} \quad \rho = r \sqrt{\frac{dg}{\sigma}}$$

- l = maximum zone length
- r = rod diameter
- d = density of liquid
- g = gravitational field
- σ = surface tension

As $r \nearrow \lambda$ approaches 2.7

If $l > r$: difficult to control melt zone

Stability: $l \sim r$ and $l = \frac{1}{2.7} \sqrt{\frac{\sigma}{dg}}$

FZT (11)

Crystal Growth

- Stirring
 - Function of the melt viscosity
 - Rotation of the feed > seed (20 vs 15 mm/hr)
- Stability of the solid phase
 - Is the crystal to be grown the most stable phase?
 - Is the melting congruent?

YVO_3 : incongruent melting when doped with Calcium

$TbMn_2O_5$: decomposes in $TbMnO_3$ and Mn_3O_4

$BiFeO_3$: $Bi_2Fe_4O_9$ and $Bi_{25}FeO_{40}$ stable phases



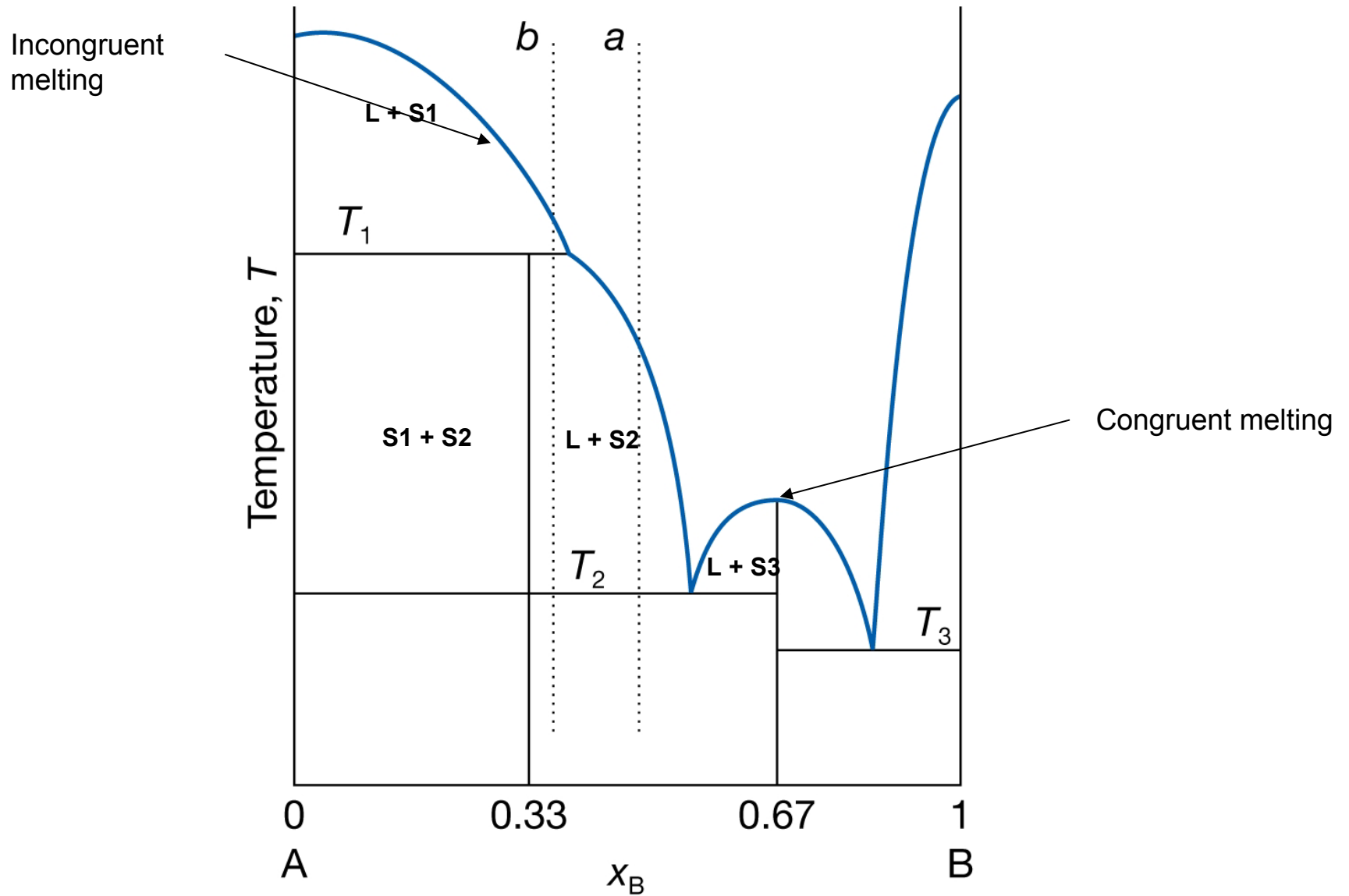
Observation of the phase diagram



XRD of the melt and of the solid phase

FZT (12)

Crystal Growth



FZT (13)

Crystal Growth

- Vapor pressure
 - Increase the pressure of the sample chamber
 - Excess of the compound with the highest vapor pressure
- Power control and overflow
- Nucleation
 - Heterogeneous nucleation (seed polycrystalline, or monocrystalline neighbor material)

Nucleation ~-particles aggregation

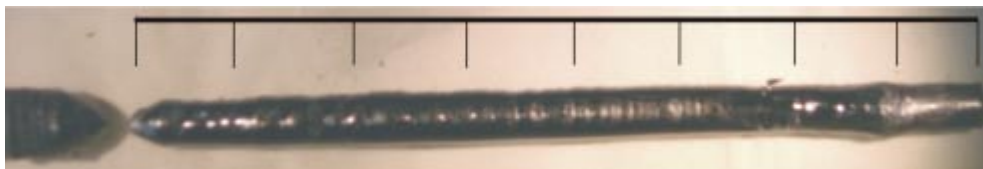
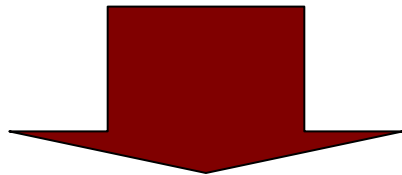
Precursors of nuclei large enough to grow are formed by association of particles in the system.

For a nucleating material A: $mA \leftrightarrow A_m$

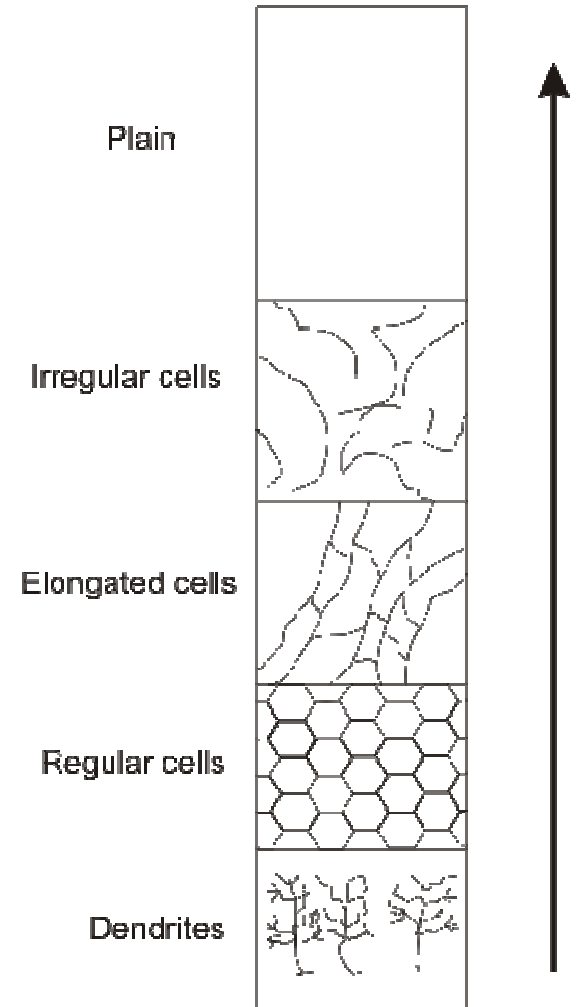
For large m and equilibrium constants: growth of nucleation!

FZT (14)

- Formation of cells
- Growth rate
 - RTiO_3 : 5 mm/hr
 - RMnO_3 orth.: 10 mm/hr
 - RMnO_3 hex.: 4 mm/hr ; 1.5 mm/hr if doped with Ca.
 - RVO_3 : 2 mm/hr
 - TbMn_2O_5 : 1.5mm/hr



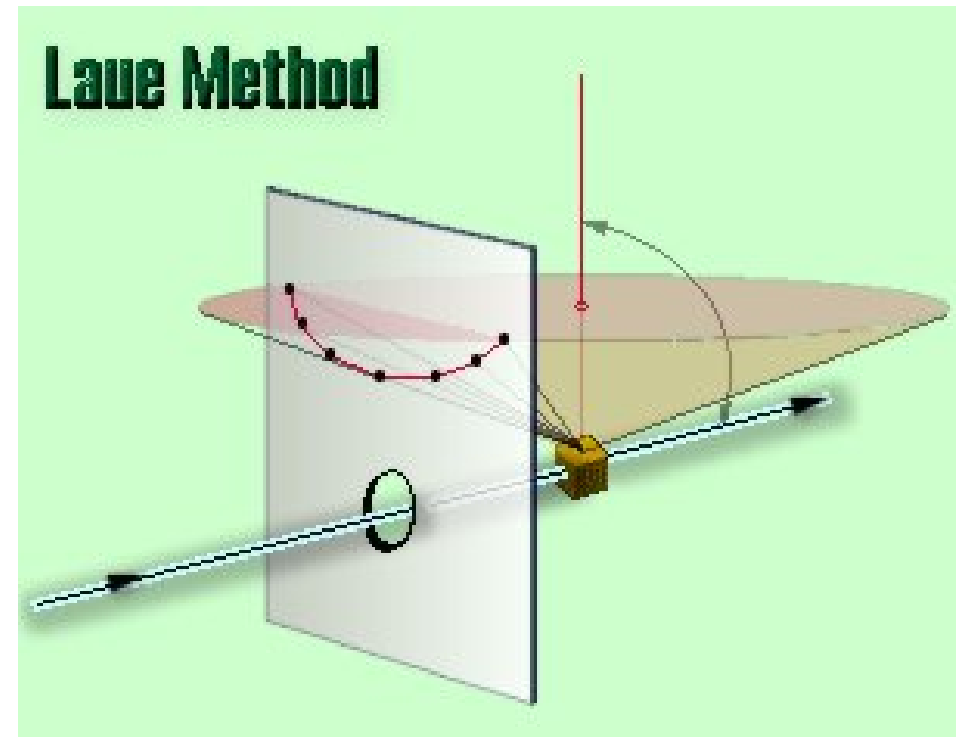
Crystal Growth



Characterization

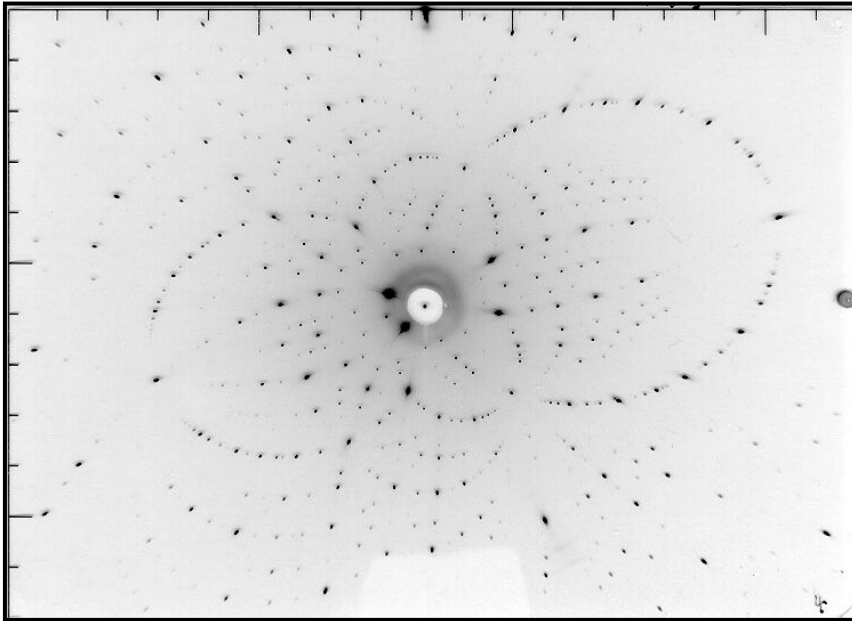
(1)

- Crystallinity
 - Back-reflection Laue method.
 - Diffracted beams form arrays of spots.
 - Bragg angle fixed for every set of planes in the crystal.
 - The positions of the spots on the film depend on the orientation of the crystal relative to the incident beam.
 - Determine crystallinity, orientation and perfection, from size and shape of spots.



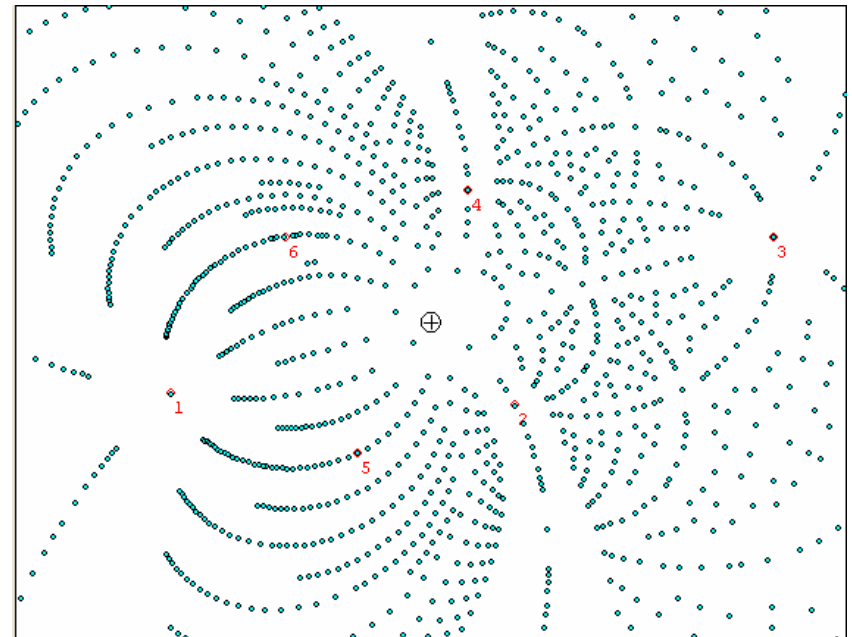
Characterization

(2)



- Input supposed crystal structure
- Input coordinates (manually or by scanning the film)
- Chose the most important coordinates
- Simulate a Laue pattern

- Find a good simulation match
- Index hkl's , simulate rotations in order to get the desired orientation for the crystal
- Take another Laue picture after necessary changes
- Check the validity of the orientation by same process



Characterization

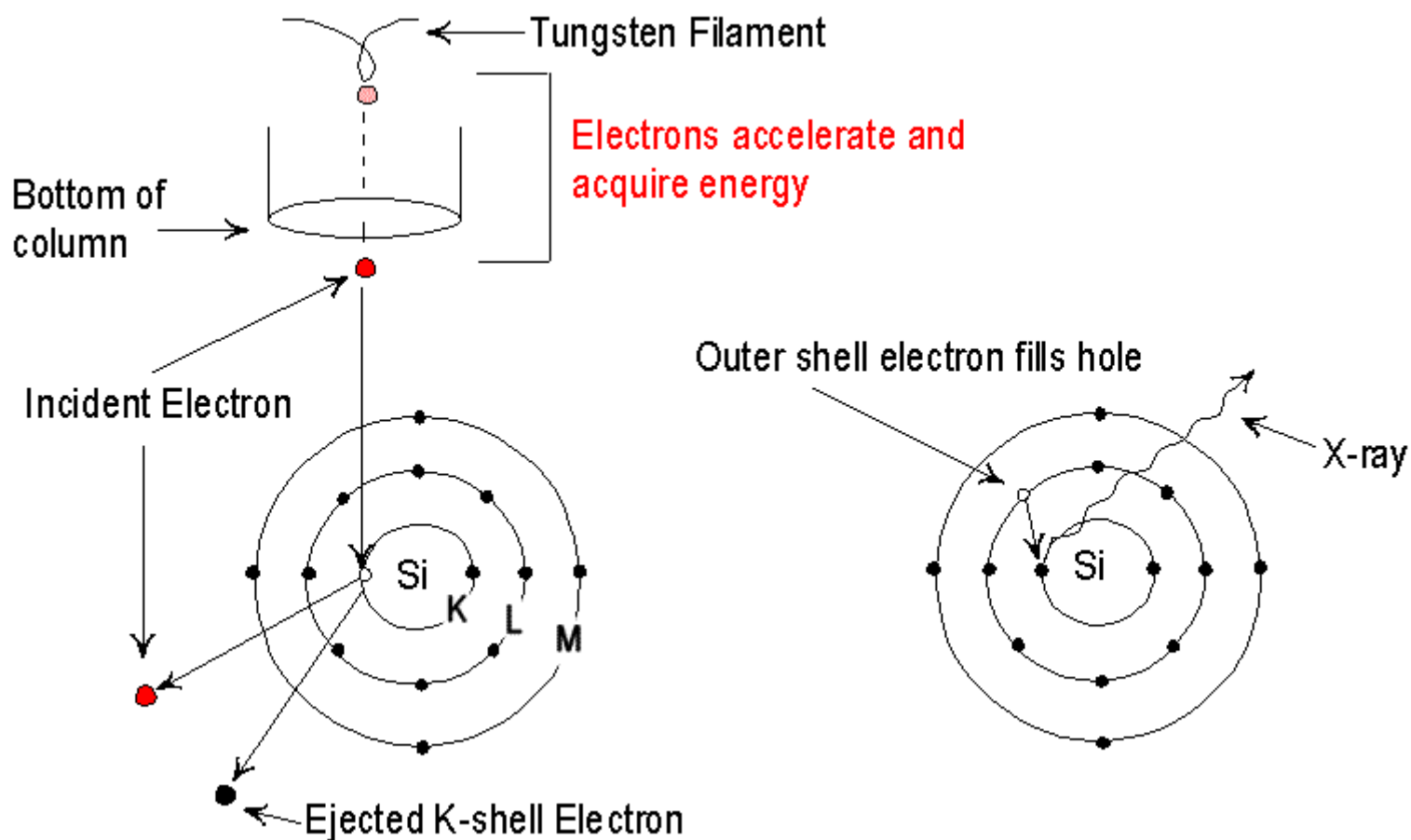
(3)

- Composition
 - Powder X-Ray diffraction
 - Crushed single crystal → use of sieve
 - Evidence for extra crystalline phases
 - Structural refinements
 - Single Crystal X-Ray diffraction
 - Size dependence
 - Evidence for extra crystalline phases
 - Evidence for twinning
 - Orientation
 - Structural refinements

Characterization

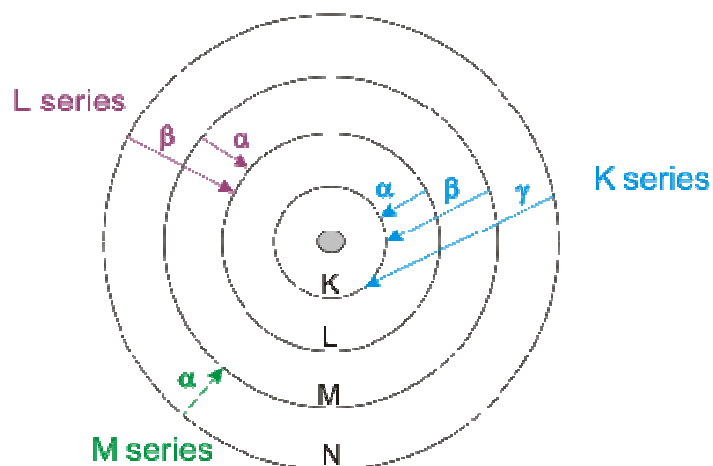
(4)

- Energy / Wavelength dispersive X-Ray analysis (EDX / WDX)



Characterization

(5)



- Electron beam energy up to 40 keV
- Area : from 0.5 microns
- Depth: 0.5 to 2 microns → Not surface technique!
- Detector

WDX

- Classifies and counts impinging X-Rays of characteristic wavelengths
- Tuned for a single wavelength at a time

Advantages

- Very high energy resolution,
- Better accuracy
- Lower background noise: more accurate quantification

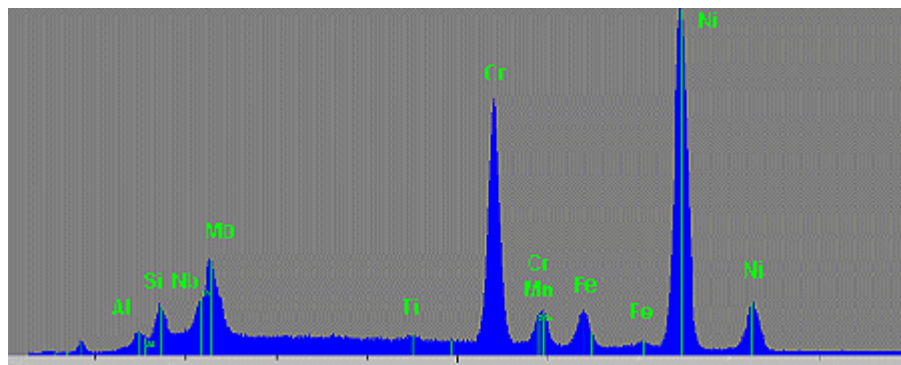
Limitations

- Very high time consumption
- Chamber contamination because of high beam current
- Very high costs

Characterization

(6)

Quantification

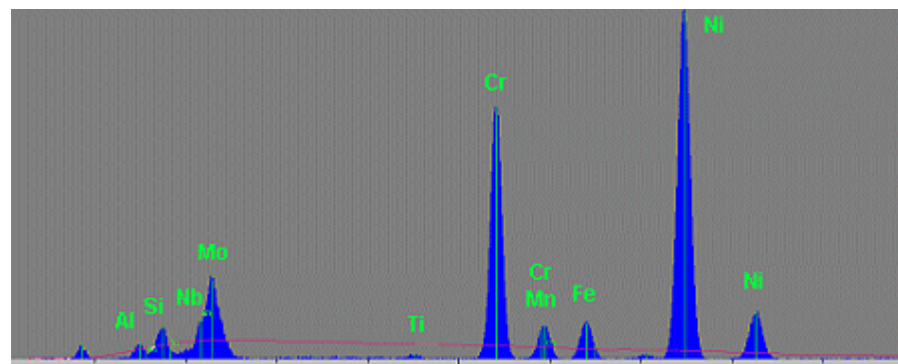


Standard

- No ZAF algorithm
- Comparison to standard files
- Standard files taken in EXACT same conditions
- Better in case of overlapping peaks or trace elements

Standard less

- Calculation of the area under each peak
- Accounts for acceleration voltage
- Sensitivity factors that convert area into weight/ atomic %
- Gaussian fit + ZAF algorithm



Conclusions

- Melt growth is one of the most controllable process
- FZT / TSFZT

Advantages

- No crucible contamination
- Shape control
- Impurity control
- Surface tension control
- Vapor pressure control
- Atmosphere control
- Large growth rates
- Large grown crystals

Limitations

- High melting compounds
- Expensive technique
- Incongruent melting
- Phase separation and stability
- Sensitivity of control parameters
- Overflows

- Widely available and powerful characterization techniques

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